

# Plan 53C

**Description:** Plan 53C utilizes a reference line from the process in the seal chamber as a pressure source to a PISTON ACCUMULATOR. Provides a PRESSURIZED system greater than the process pressure being sealed, providing clean BARRIER fluid to a dual seal “arrangement 3”. Circulation is by an internal pumping ring.

**Objective:** Same as Plan 53A, but will handle higher pressures and maintain a constant differential pressure above process pressure on the inboard seal.

**Advantages:** Same as Plan 53B. Minimizes pressure reversals and maintains process seal stability.

